

Micro-Pattern Gas Detectors (RD51) Workshop

Thursday, 17 April 2008

Relations with Industry (09:40 - 10:30)

-Conveners: Jan Visschers

time	[id] title	presenter
09:40	[33] GEM development with Tech-Etch for future detector applications	Dr SIMON, Frank
10:00	[34] Techtra [Wroclaw Technology Park]	MACIEJ, Chorowski
10:10	[35] PANalytical	BETHKE, Klaus